

09/686,895

	L #	Hits	EAST Search Text	DBs	Time Stamp	Type
1	L1	7	((("5745594") or ("5962862") or ("5987172") or ("5943441"))).PN.	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 17:52	IS&R
2	L2	11106 5	(camera OR image OR video OR picture OR photo OR photograph) WITH (merg\$3 OR combin\$3 OR join\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:19	BRS
3	L3	3382	wafer WITH fragment\$6	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 17:58	BRS
4	L4	19	L2 AND L3	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:12	BRS
5	L5	9	("4713551"   "4786816"   "5466945"   "5471541"   "5644140"   "5796486"   "5798532"   "5852300"   "6324298").PN.	USPAT	2004/03/11 17:59	BRS
6	L6	3	5644140.URPN.	USPAT	2004/03/11 18:03	BRS
7	L7	219	log WITH (cyclical OR recycl\$3 OR recirculat\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:55	BRS
8	L8	16	L7 SAME (trigger\$3 OR signal\$4 OR stop\$4 OR activat\$3 OR prompt\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:25	BRS
9	L9	6	L7 SAME (camera OR image OR video OR picture OR photo OR photograph)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:26	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Type
10	L1 0	22	L7 SAME (monitor\$3 OR check\$3 OR inspect\$3 OR examin\$3 OR observ\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:25	BRS
11	L1 1	12605 0	(log OR history OR buffer) SAME (monitor\$3 OR check\$3 OR inspect\$3 OR examin\$3 OR observ\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:27	BRS
12	L1 2	39067	L11 SAME (trigger\$3 OR signal\$4 OR stop\$4 OR activat\$3 OR prompt\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:30	BRS
13	L1 3	6434	L12 SAME (camera OR image OR video OR picture OR photo OR photograph)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:27	BRS
14	L1 4	56523	(log OR history OR buffer) WITH (monitor\$3 OR check\$3 OR inspect\$3 OR examin\$3 OR observ\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:27	BRS
15	L1 5	16038	L14 SAME (trigger\$3 OR signal\$4 OR stop\$4 OR activat\$3 OR prompt\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:27	BRS
16	L1 6	9104	L14 WITH (trigger\$3 OR signal\$4 OR stop\$4 OR activat\$3 OR prompt\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:50	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Type
17	L1 7	1644	L16 SAME (camera OR image OR video OR picture OR photo OR photograph)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:27	BRS
18	L1 8	1333	L16 WITH (camera OR image OR video OR picture OR photo OR photograph)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:50	BRS
19	L1 9	491	L18 AND (semiconductor OR integrated ADJ circuit OR IC OR wafer OR chip)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:28	BRS
20	L2 0	40	L18 SAME (semiconductor OR integrated ADJ circuit OR IC OR wafer OR chip)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:29	BRS
21	L2 1	2452	buffer WITH (cyclical OR recycl\$3 OR recirculat\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:49	BRS
22	L2 2	324	L21 WITH (trigger\$3 OR signal\$4 OR stop\$4 OR activat\$3 OR prompt\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:50	BRS
23	L2 3	22	L22 WITH (camera OR image OR video OR picture OR photo OR photograph)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:53	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Type
24	L2 4	2116	security SAME (photo OR picture OR camera) SAME (history OR stor\$3 OR archiv\$3 OR buffer\$4 OR log\$4)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:55	BRS
25	L2 5	5002	security SAME (photo OR picture OR camera OR image) SAME (history OR stor\$3 OR archiv\$3 OR buffer\$4 OR log\$4)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:54	BRS
26	L2 6	1533	security WITH (photo OR picture OR camera OR image) WITH (history OR stor\$3 OR archiv\$3 OR buffer\$4 OR log\$4)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:13	BRS
27	L2 7	5	L26 WITH (cyclical OR recycl\$3 OR recirculat\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:13	BRS
28	L2 8	5	L26 SAME (cyclical OR recycl\$3 OR recirculat\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 18:57	BRS
29	L2 9	52	L26 SAME (temporar\$3 OR permanent\$2)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:03	BRS
30	L3 0	50	event WITH log\$4 WITH (cyclical OR recirculat\$3 OR recycl\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:04	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Type
31	L3 1	16287	monitor\$3 WITH (photo OR picture OR camera OR image) WITH (history OR stor\$3 OR archiv\$3 OR buffer\$4 OR log\$4)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:13	BRS
32	L3 2	600	L31 WITH (temporar\$3 OR permanent\$2 OR cyclical\$2 OR recycl\$3 OR recirculat\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:15	BRS
33	L3 3	3	L31 WITH (temporar\$3 OR permanent\$2) WITH (cyclical\$2 OR recycl\$3 OR recirculat\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:18	BRS
34	L3 4	4	3804978.URPN.	USPAT	2004/03/11 19:16	BRS
35	L3 5	2	3900706.URPN.	USPAT	2004/03/11 19:16	BRS
36	L3 6	3	RE31239.URPN.	USPAT	2004/03/11 19:17	BRS
37	L3 7	9	L31 SAME (temporar\$3 OR permanent\$2) SAME (cyclical\$2 OR recycl\$3 OR recirculat\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:26	BRS
38	L3 8	15	("4555561"   "4752897"   "5070468"   "5192999"   "5208745"   "5210526"   "5258837"   "5260878"   "5270811"   "5278643"   "5284164"   "5353238"   "5412400"   "5416725"	USPAT	2004/03/11 19:19	BRS
39	L3 9	83973	von buhr.xa,xp.	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:26	BRS
40	L4 0	337	von ADJ buhr.xa,xp.	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:27	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Type
41	L4 1	84	L40 AND buffer	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:28	BRS
42	L4 2	2	L41 AND recirculat\$3	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:28	BRS
43	L4 3	47	napiorkowski.xa,xp.	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:28	BRS
44	L4 4	21	L43 AND buffer	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:28	BRS
45	L4 5	1	L44 AND recirculat\$3	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:29	BRS
46	L4 6	232	(L40 OR L43) AND log\$4	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:31	BRS
47	L4 7	4	(L40 OR L43) AND recirculat\$3	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:29	BRS

	L #	Hits	Search Text	DBs	Time Stamp	Type
48	L4 8	191	L46 AND (trigger\$3 OR signal\$4 OR stop\$4 OR activat\$3 OR prompt\$3)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:31	BRS
49	L4 9	0	L48 AND eent	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:31	BRS
50	L5 0	100	L48 AND event	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:31	BRS
51	L5 1	49	(L40 OR L43) AND log\$4 SAME event	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:37	BRS
52	L5 2	57	L50 NOT L51	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:41	BRS
53	L5 3	125	L46 NOT (L42 OR L45 OR L47 OR L50 OR L51)	USPAT; US-PGPU B; EPO; JPO; DERWEN T; IBM_TDB	2004/03/11 19:43	BRS
54	L5 4	24	("4878167"   "5155678"   "5191651"   "5280611"   "5339427"   "5345590"   "5394554"   "5410695"   "5463736"   "5471631"   "5485608"   "5493668"   "5530850"   "5537574"   "5537588"   "5551003"   "5737600"   "5832515"   "5920875"   "5956735"   "5999935"   "6076095"   "6092084"   "6125393").PN.	USPAT	2004/03/11 19:47	BRS

	1	Document ID	Source	Issue Date	Title	Current OR	Inventor	2	3	4	5
1	<input checked="" type="checkbox"/>	US 20030202178 A1	US-PG PUB	20031030	Semiconductor wafer inspection apparatus	356/237.2	Tsuji, Haruyuki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>
2	<input checked="" type="checkbox"/>	US 20010043735 A1	US-PG PUB	20011122	DETECTION OF WAFER FRAGMENTS IN A WAFER PROCESSING	382/149	SMARGIASSI, EUGENE et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3	<input checked="" type="checkbox"/>	US 6535628 B2	USPAT	20030318	Detection of wafer fragments in a wafer processing apparatus	382/149	Smargiassi, Eugene et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4	<input type="checkbox"/>	CN 1405853 A	DERW ENT	20030326	Method for tracing wafer boundary		XU, Q	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>
5	<input checked="" type="checkbox"/>	WO 200022655 A	DERW ENT	20030507	Wafer fragments analyzing system for semiconductor production, has image acquisition device to acquire image of wafer edge portion where illumination source generates back-illuminating radiation for wafer		AHMAD, W R et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
6	<input checked="" type="checkbox"/>	US 6064429 A	USPAT	20000516	Foreign object video detection and alert system	348/128	Belk, John Huntley et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
7	<input type="checkbox"/>	US 5909276 A	USPAT	19990601	Optical inspection module and method for detecting particles and defects on substrates in integrated process tools	356/237.2	Kinney, Patrick D. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
8	<input type="checkbox"/>	US 5659630 A	USPAT	19970819	Advanced manufacturing inspection system	382/149	Forslund, Donald Charles	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
9	<input type="checkbox"/>	US 5592295 A	USPAT	19970107	Apparatus and method for semiconductor wafer edge inspection	356/426	Stanton, Leslie G. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
10	<input type="checkbox"/>	US 4812664 A	USPAT	19890314	Apparatus for scanning a flat surface to detect defects	250/559.18	Borden, Peter G.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
11	<input type="checkbox"/>	US 4659220 A	USPAT	19870421	Optical inspection system for semiconductor wafers	356/237.5	Bronte, Joseph J. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
12	<input type="checkbox"/>	US 4352016 A	USPAT	19820928	Method and apparatus for determining the quality of a semiconductor surface	250/358.1	Duffy, Michael T. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
13	<input type="checkbox"/>	US 4652757 A	USPAT	19870324	Method and apparatus for optically determining defects in a semiconductor material	250/360.1	Carver, Gary E.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
14	<input checked="" type="checkbox"/>	US 6452150 B1	USPAT	20020917	Cassette measuring system	250/208.1	Mori, Kunihiro et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
15	<input type="checkbox"/>	US 6324298 B1	USPAT	20011127	Automated wafer defect inspection system and a process of performing such inspection	382/149	O'Dell, Jeffrey et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
16	<input type="checkbox"/>	US 5644140 A	USPAT	19970701	Apparatus for checking semiconductor wafers with complementary light sources and two cameras	250/559.08	Biedermann, Ernst et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
17	<input type="checkbox"/>	JP 2002163463 A	DERW ENT	20020607	Object utilization log management method in operating system, involves storing monitoring data that recycles utilization log of object in memory			<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>

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	1	Document ID	Source	Issue Date	Title	Current OR	Inventor	2	3	4	5
18	<input type="checkbox"/>	US 6404498 B1	USPAT	20020611	Manufacturing method of semiconductor substrate and method and apparatus for inspecting defects of patterns on an object to be	356/394	Maeda, Shunji et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
19	<input type="checkbox"/>	US 6265736 B1	USPAT	20010724	Image pick-up apparatus	257/232	Dillen, Bartholomeus G. M. H. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
20	<input type="checkbox"/>	US 6263099 B1	USPAT	20010717	Manufacturing method of semiconductor substrate and method and apparatus for inspecting defects of patterns of an object to be	382/149	Maeda, Shunji et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
21	<input type="checkbox"/>	US 5774222 A	USPAT	19980630	Manufacturing method of semiconductor substrate and method and apparatus for inspecting defects of patterns on an object to be inspected	356/394	Maeda, Shunji et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
22	<input type="checkbox"/>	US 5412705 A	USPAT	19950502	X-ray examination apparatus with an imaging arrangement having a plurality of image sensors	378/98.3	Snoeren, Rudolph M. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
23	<input type="checkbox"/>	US 5771374 A	USPAT	19980623	Event driven programmer logic controller processor arrangement with buffered inputs and method of operation of the same	713/502	Burshtein, Anat et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
24	<input checked="" type="checkbox"/>	US 5625572 A	USPAT	19970429	Multimedia process monitor and control system	702/183	Yonekura, Toshiaki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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	1 [1]	Document ID	Source	Issue Date	Title	Current OR	Inventor	2 [1]	3	4	5
1	<input checked="" type="checkbox"/>	US 4638289 A	USPA T	19870120	Accident data recorder	246/45	Zottnik, Edmund	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2	<input checked="" type="checkbox"/>	US 6163338 A	USPA T	20001219	Apparatus and method for recapture of realtime events	348/148	Johnson, Dan et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>